

[לוגו, תמונה וכו']

נקודת המבט של המבקש

מפגש עם בוחני רשות הפטנטים, 25.2.2020

עינב זילבר, עורכת פטנטים, עו"ד
זילבר עריכת דין . פטנטים . ניהול קניין רוחני

קצת עלי ועל נושאי השיחה

About Me:

- Academic Background: BSc Physics & Math, LLB
- Professional Background: Patent Attorney, Adv.
- Experience: Law firm experience, Industry experience
- Volunteering: IPAA - Chair, IL Forum for IP Managers (co-founder), IATI – Technical Training to ILPO Examiners
- Recognition: Corporate IP Star by Managing IP specialist guide

נושאי השיחה:

- מי הוא המבקש?
- מה עושים עם פטנטים?
- מה האימפקט של החלטות הבוחנים?
- ניהול פורטפוליו פטנטים בחברות
- הערה – בקשת פטנט ארעית
- העתיד כבר כאן

מי הוא המבקש?

USA, 2014:

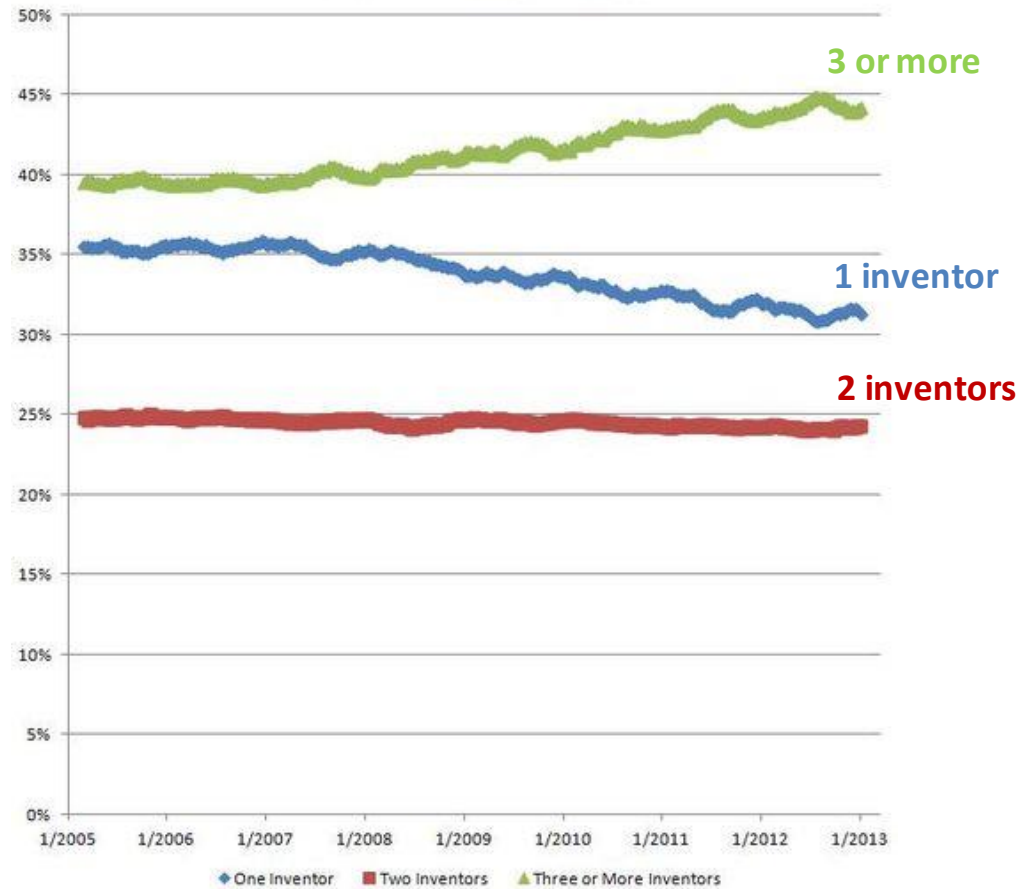
- Total grants: 300,678
- Grants by ownership:
 - Corporations: 280,074 (93.1%)
 - Government: 1345 (0.5%)
 - Individuals: 19259 (6.4%)
- 1000 grants in 2014 $\geq$ 32 corporations
- 40 grants in 2014 $\geq$ 844 corporations
 - Holding 63% of grants
- < 40 grants in 2014 – 37,568 corporations

US, 2019:

- Total grants: 333530
- Top 50 holds 27%
- Top 5:
 1. IBM 9262 (active families 37,304)
 2. Samsung 6469 (76,638)
 3. Canon 3548 (35,724)
 4. Microsoft 3081 (29,824)
 5. Intel 3020 (24,628)

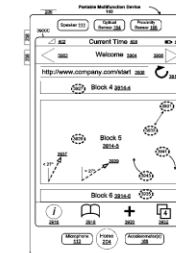
איך נוצרות אמצאות?

**Inventor Count: Inventors Per Patent
20-Week Moving Average**



25

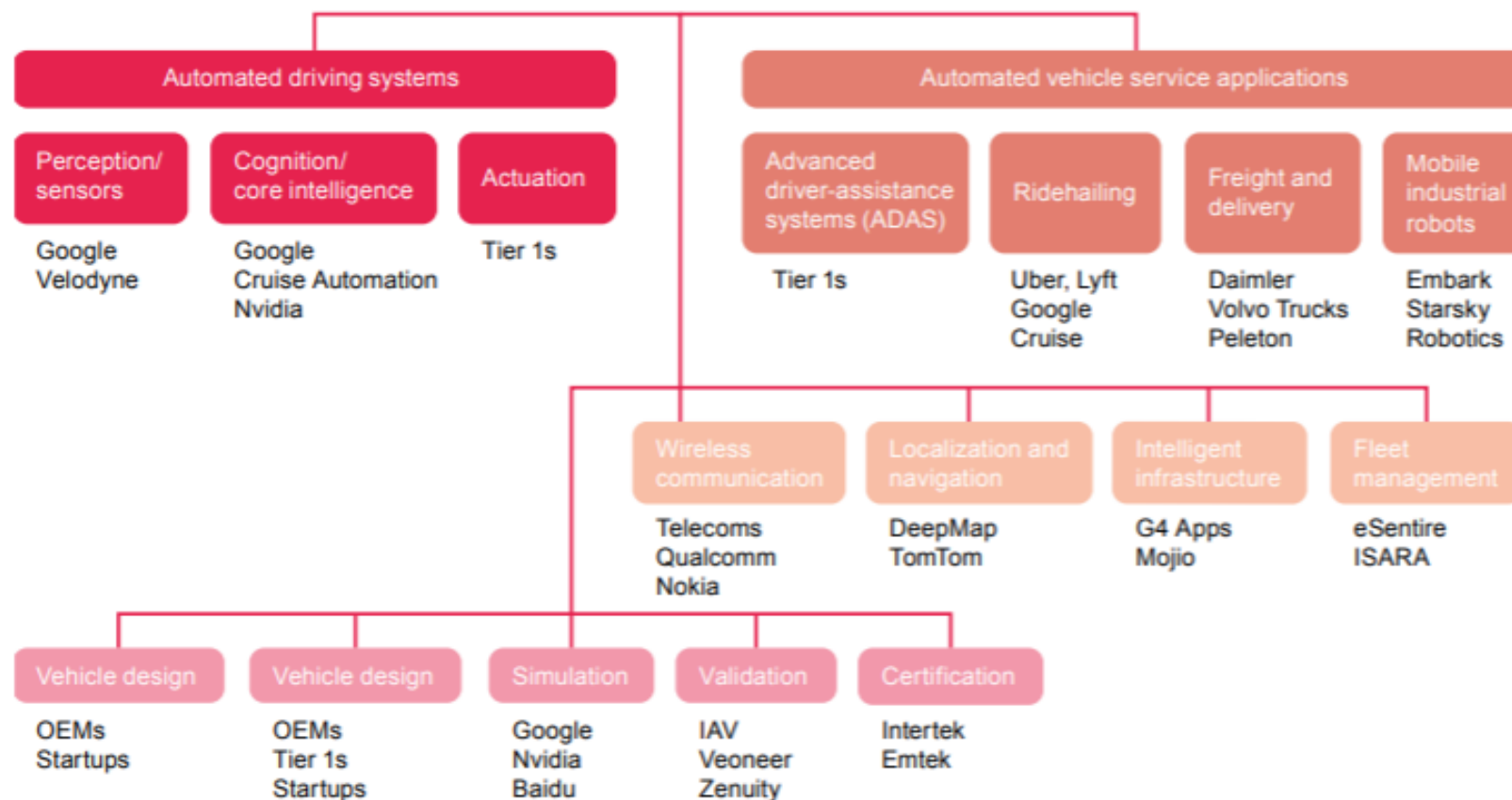
(12) United States Patent Jobs et al.		(10) Patent No.: US 7,479,949 B2
		(45) Date of Patent: *Jan. 20, 2009
(54) TOUCH SCREEN DEVICE, METHOD, AND GRAPHICAL USER INTERFACE FOR DETERMINING COMMANDS BY APPLYING HEURISTICS		(65) Prior Publication Data US 2008/0174570 A1 Jul. 24, 2008
(75) Inventors: Steven P. Jobs , Palo Alto, CA (US); Scott Forstall , Mountain View, CA (US); Greg Christie , San Jose, CA (US); Stephen O. Lemay , San Francisco, CA (US); Scott Herz , San Jose, CA (US); Marcel van Os , San Francisco, CA (US); Bas Ording , San Francisco, CA (US); Gregory Novick , Santa Clara, CA (US); Wayne C. Westerman , San Francisco, CA (US); Imran Chaudhri , San Francisco, CA (US); Patrick Lee Coffman , Menlo Park, CA (US); Kenneth Kocienda , Sunnyvale, CA (US); Nitin K. Ganatra , San Jose, CA (US); Freddy Allen Anzures , San Francisco, CA (US); Jeremy A. Wyld , San Jose, CA (US); Jeffrey Bush , San Jose, CA (US); Michael Matas , San Francisco, CA (US); Paul D. Marcos , Los Altos, CA (US); Charles J. Pisula , San Jose, CA (US); Virgil Scott King , Mountain View, CA (US); Chris Blumensberg , San Francisco, CA (US); Francisco Ryan Tolmasky , Cupertino, CA (US); Richard Williamson , Los Gatos, CA (US); Andre M. J. Boule , Sunnyvale, CA (US); Henri C. Lamiroux , San Carlos, CA (US)		Related U.S. Application Data (63) Continuation of application No. 11/850,635, filed on Sep. 5, 2007. (60) Provisional application No. 60/937,993, filed on Jun. 29, 2007, provisional application No. 60/937,991, filed on Jun. 29, 2007, provisional application No. 60/879,469, filed on Jan. 8, 2007, provisional application No. 60/879,253, filed on Jan. 7, 2007, provisional application No. 60/824,769, filed on Sep. 6, 2006.
(73) Assignee: Apple Inc. , Cupertino, CA (US)		(51) Int. Cl. G09G 5/00 (2006.01) G06F 3/048 (2006.01)
(*) Notice: Subject to any disclaimer, the term of this patent is extended or adjusted under 35 U.S.C. 154(b) by 0 days. This patent is subject to a terminal disclaimer.		(52) U.S. Cl. 345/173 ; 345/169; 715/786; 715/784 (58) Field of Classification Search 345/156, 345/157, 173-181 See application file for complete search history.
(21) Appl. No.: 12/101,832		(56) References Cited U.S. PATENT DOCUMENTS 5,528,260 A * 6/1996 Kent 345/684 5,655,094 A * 8/1997 Cline et al. 715/786 5,805,161 A * 9/1998 Tiphane 715/786 6,278,443 B1 8/2001 Amro et al. 345/173 6,466,203 B2 10/2002 Van Fe 345/173 6,559,869 B1 * 5/2003 Lui et al. 715/785 6,597,345 B2 * 7/2003 Hirschberg 345/168 6,657,615 B2 12/2003 Harada 345/173 6,683,628 B1 * 1/2004 Nakagawa et al. 715/799 6,690,387 B2 2/2004 Zimmerman et al. 345/684 7,088,344 B2 8/2006 Maczawa et al. 345/173 7,093,203 B2 8/2006 Mugura et al. 715/864 2002/0158838 A1 10/2002 Smith et al. 345/156 2003/0184593 A1 10/2003 Dunlop 345/810 2004/0012572 A1 1/2004 Sowden et al. 345/173 2004/0021676 A1 2/2004 Chen et al. 345/684 2004/0160420 A1 8/2004 Baharav 345/173 2005/012723 A1 1/2005 Pallakoff 345/173 2005/0193351 A1 9/2005 Huoviala 715/840
(22) Filed: Apr. 11, 2008		



איך מפותחים מוצרים?

Mapping the involvement of AV companies

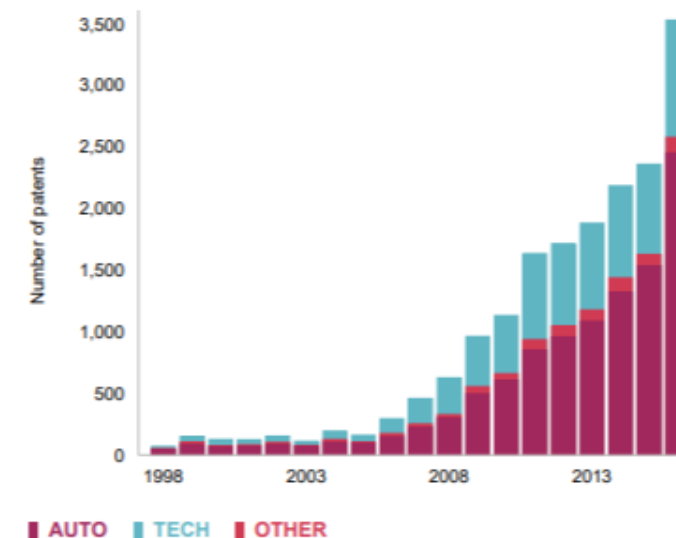
Figure 3.7 Examples of companies working in various AV technologies



Source: Center for Automotive Research (CAR).

The rise of AI, robotics and mobility services is the main driver of the technological shift in the mid-2000s

Figure 3.5 Sectoral breakdown of AV-related patents by frequency

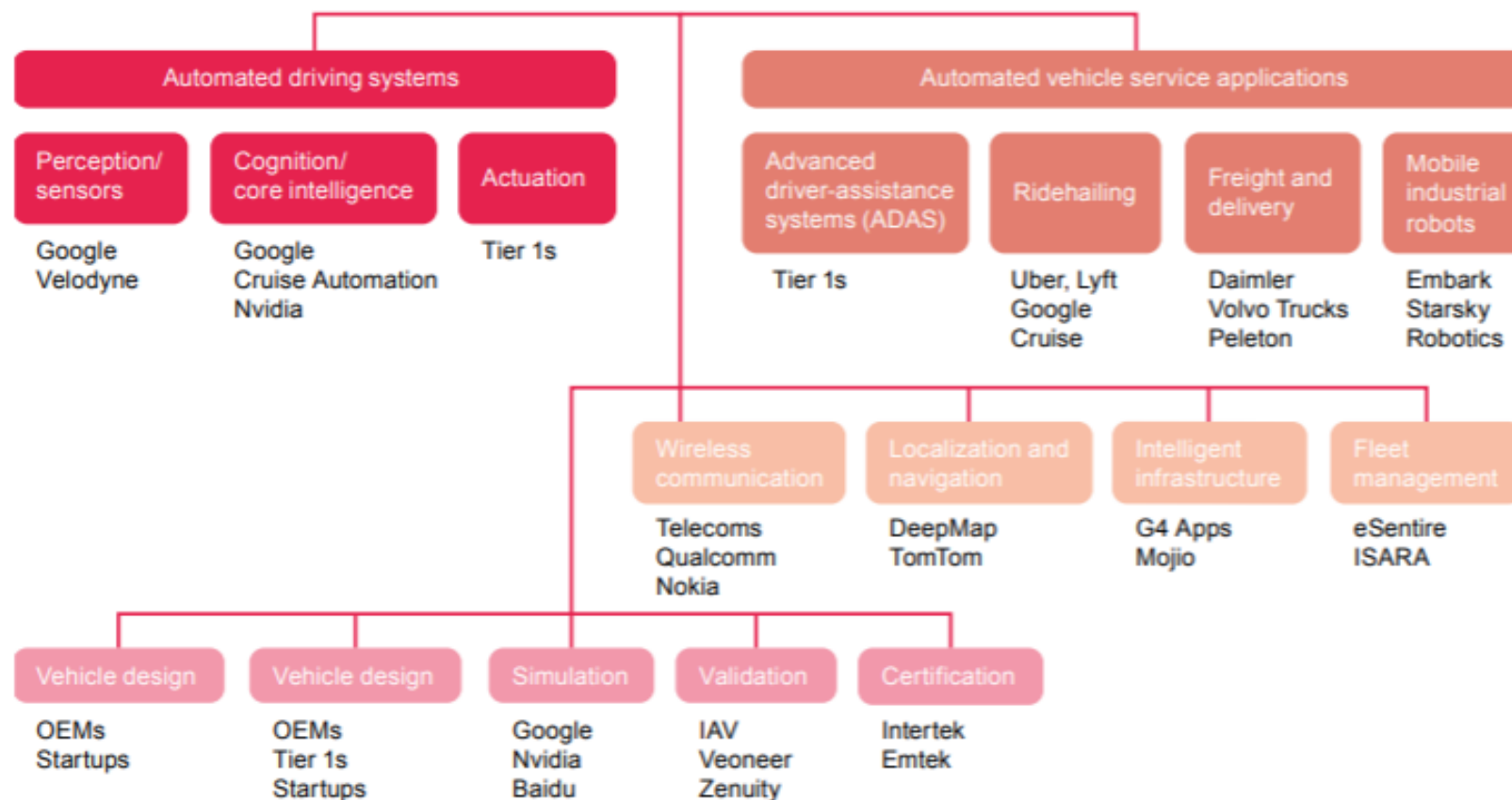


Source: WIPO based on PATSTAT and PCT data (see Technical Notes).

איך מפותחים מוצרים?

Mapping the involvement of AV companies

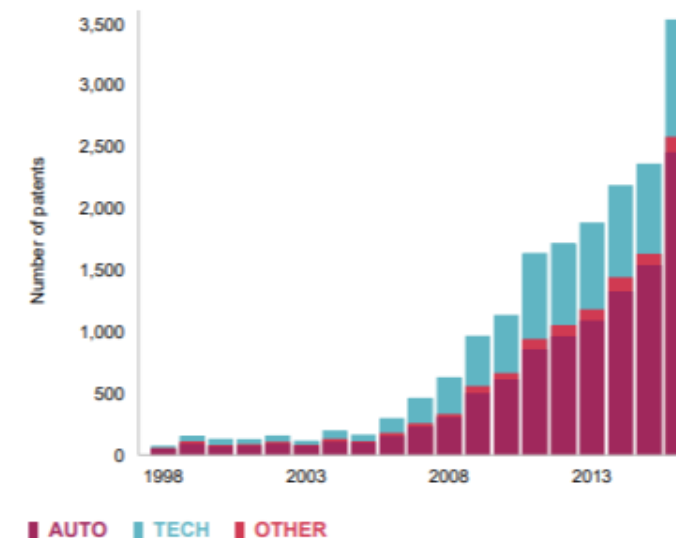
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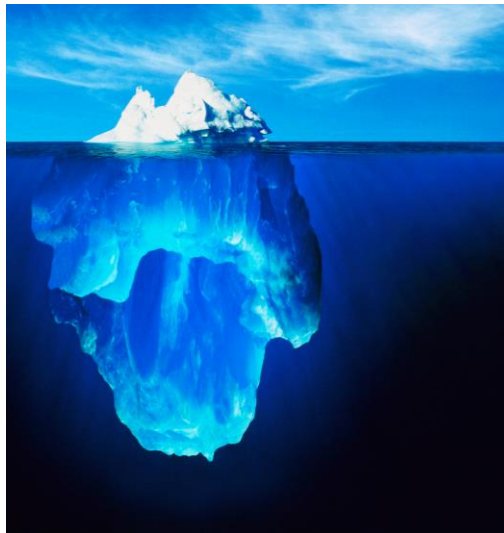
Source: WIPO based on PATSTAT and PCT data (see Technical Notes).

מה עושים עם פטנטים?

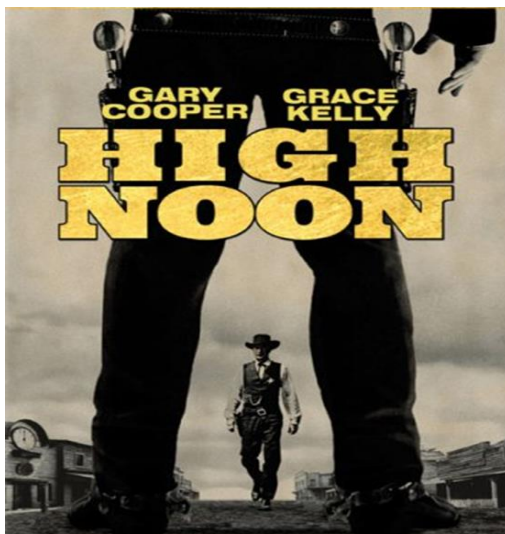
**Disruptive
Technologies**



**Controlled
Publication**



Competition



Big Players



מה עושים עם פטנטים?

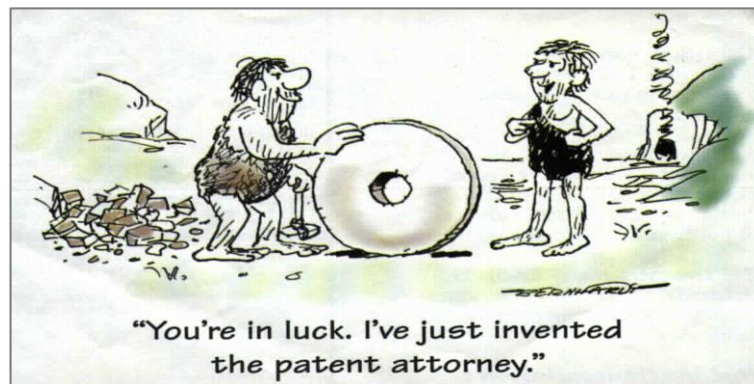
A product
of team
Innovation



The
subject of
various
processes



A platform for
collaborations
and transfer of
rights



Profession,
Industry

מה האימפקט של החלטות הבוחנים?

החשיבות של פטנטים טובים עבור חברה:

- 1 – הסיכון בפטנט צר מדי
- 2 – הסיכון בפטנט רחב מדי
- 3 – קיבול מיידי של הבקשה
- 4 – משפחת פטנטים בינלאומית – ציטוטים שונים במדינות שונות

החשיבות של מרשם הפטנטים עבור חברה:

- 1 – הסיווג כמפתח למיפוי, סינון וניתוח
- 2 – זמינות המידע
- 3 – גישה למסמכים ממקום אחד
- 4 – מידע על סטטוס

כשהמבקש מזהה פטנט רלוונטי של אחר:

- 1 – אני לא מפר
- 2 – הפטנט לא תקף
- חזקת התקפות
- ידע קודם נוסף
- 3 – דרך חדשה
- מחקר, פיתוח ויישום נוספים
- 4 – הפסקת השימוש /רכישת זכויות
- ומה אם הפטנט של האחר אינו פטנט מוצדק?

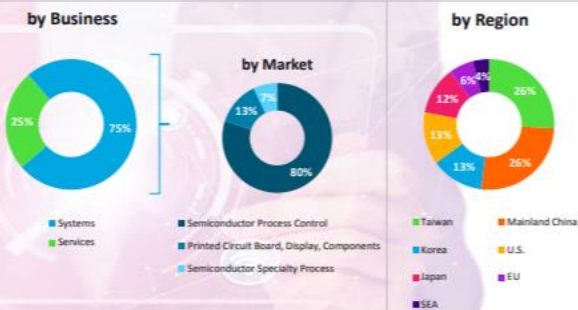
בקשת פטנט ארעית - הדוגמא של

KLA at a Glance (NASDAQ: KLAC)

KEY STATISTICS¹

FOUNDED	1976
HEADQUARTERS	Milpitas, CA
EMPLOYEES	~10,000
COUNTRIES	18
MARKET-CAP ²	\$23.8B
REVENUE ³	\$5.1B
ADJ. EBITDA ³	\$1.9B
R&D (% of Sales)	15%

2019E REVENUE SPLIT



Diversified Global Leader in Electronics Value Chain

More Complexity & Semiconductor Devices Drive Greater Demand

MEGA TRENDS ACROSS...		...KEY INDUSTRIES		
ARTIFICIAL INTELLIGENCE	5G CONNECTIVITY	MOBILE	DATA CENTER	AUTOMOTIVE
- Core engine of KLA products' performance - Clear opportunities as a user and supplier - Expanding the scope of advanced logic nodes - Significant inflections in packaging via multi-chip integration	- Embedded in technologies in the next 5 years - Building infrastructure increases demand for KLA - Mobile implementation in 2021E-2023E, driving new smartphone cycle - Significant opportunities across our entire portfolio	#1 consumer of semiconductor (\$100B+ / year) >30% growth of semiconductor content in future 5G phones - Leading with new technology inflections - Highest process control intensity industry	- High growth industry - Strong driver of leading-edge semiconductor - End customers designing their own chips - Strategic collaborations to influence semiconductor supply chain	- Secular transformation with connectivity/autonomous/electrification - Fastest growing semiconductor segment - Highest semiconductor quality and reliability standards

KLA is Differentiated with Solution Centric and Product Agnostic Approach

US10095122:

KLA-Tencor Invention Disclosure Form		Disclosure No.
1. INVENTORS		P.000
Myoungjun Lee and Mark D. Smith		
2. TITLE OF THE INVENTION (MUST BE FILLED OUT)		
Sub-Resolution Assist Feature Engineering for Designing Metrology Targets to Reduce PPE Bias		
8. RELATED PRINTED PUBLICATIONS, PATENTS, PATENT APPLICATIONS, PLEASE ATTACH COPIES		
KT Invention Disclosure P7114, PCT Application No. PCT/US20/24114 (Mad. Apr. 15, 2016)		
[1] Registration target design for managing both reticle grid error and wafer overlay, US 760842 B1		
[2] Structure and method for simultaneously determining an overlay accuracy and pattern placement error, US 7607842 B2		
[3] "Overlay metrology solutions in a single patterning scheme", SPIE Vol. 9424-14240E, 2015		
[4] Myoungjun Lee, Mark D. Smith, J. Lee et al., "Calibration-aware overlay metrology target design method," SPIE Advanced Lithography, San Jose, CA, USA, Proc. of SPIE Vol. 9778-1L, Feb. 2016		
[5] Myoungjun Lee, Mark D. Smith, Mike Abd, et al., "Metrology target design (MTD) solution for alignment-corrected (ACD) optics," SPIE Advanced Lithography, San Jose, CA, USA, Proc. of SPIE Vol. 9778-17782K, Feb. 2016		
[6] Myoungjun Lee and Mark D. Smith, "Highly sensitive focus monitoring technique based on illumination and target co-optimization," SPIE Advanced Lithography, Proc. SPIE 9778-2L, 2016		
USE THE ATTACHED SHEETS TO ANSWER THE FOLLOWING QUESTIONS. PLEASE AT LEAST BRIEFLY ANSWER ALL QUESTIONS.		
1. GENERAL PURPOSE OF THE INVENTION. STATE IN GENERAL TERMS THE OBJECTS OF THE INVENTION.		
The objective of this invention is the design and/or optimization of design of metrology targets to be used for monitoring overlay between different layers during semiconductor manufacturing. This invention enables the design and/or optimization of metrology targets that will have the improved target prioritization (i.e., larger process window) on the wafer as well as the improved device-to-target matching by reducing the placement error offset between the target and the device. By optimally designing patterns in the reticle, the final ACD patterns on the wafer will be same as the designer intended with improved prioritization and reduced pattern placement error (PPE) bias between the device and metrology targets. This is the completely new method and it will be used for both ACD and SCAL targets with different types of exposure illumination.		
16. BACKGROUND INFORMATION (PPE) FIELD OF USE:		
In the field of semiconductor metrology, a metrology tool may comprise an illumination system which illuminates a target, a collection system which captures relevant information provided by the illumination system's interaction (or lack thereof) with a target, device or feature, and a processing system which analyzes the information collected using one or more algorithms. Metrology tools can be		



KLA-Tencor

Sub-resolution assist feature (SRAF) engineering for designing metrology targets to reduce PPE bias



Goals

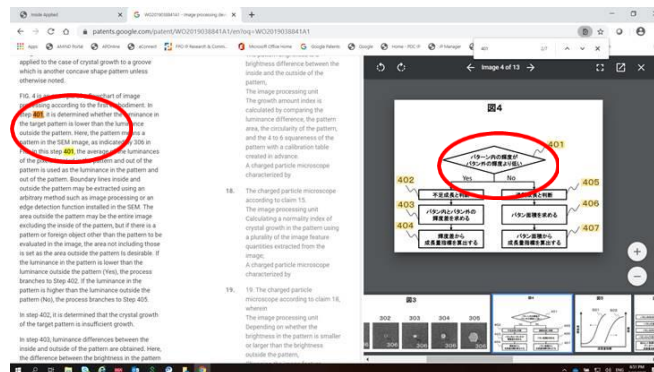
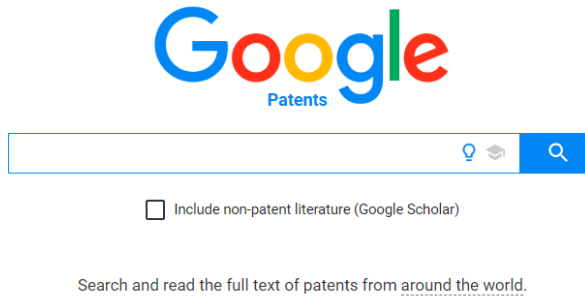
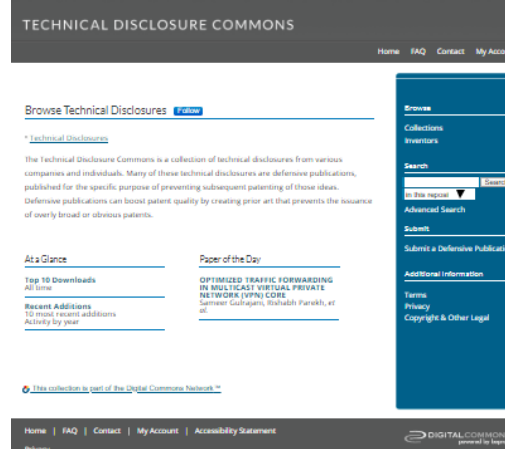
- Designing metrology targets in the reticle using sub-resolution features in order to print the targets as a designer intended while significantly minimizing the PPE bias between the device and metrology targets
- The proposed new target design will:
 - reduce the pattern placement error bias between the device and the target
 - improve the metrology measurement performance
- This method can be used for many different types of illumination.
- This method is not for the layer using SADP or SAQP processes, which requires to use the segmented target.

- PPE: pattern placement error
- SRAF: Sub-Resolution Assist Feature
- SRF: Sub-Resolution Inverse Feature
- LA: Lens Aberration
- MTD: Metrology target design
- SCOL: Scatterometry overlay
- ABE: imaging based overlay
- AOI: After develop inspection



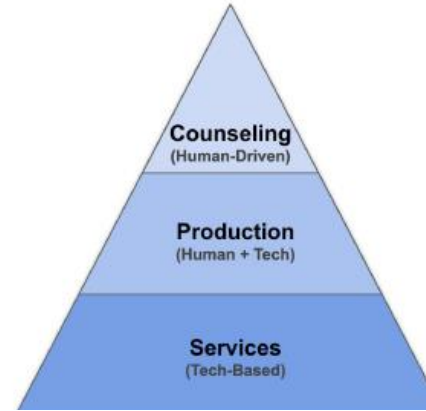
Elevating the bar of Novelty: non-patent publications

Elevating the bar of Novelty: overcoming language barriers



העתיד כבר כאן:

Patent Practice 3.0: New Paradigm, New Tools



Invention intake	BRIGHT MARBLES	Legit	Wellspring	MindMatters Solutions	AppColl
Prior art searching	NLPatent	DOROTHY	amplified	ambercile	RESOLUTE patents
Application drafting	Specificio	Draft Builders	HOLLAND & HART	HARRITY	[TurboPatent]
Patent proofreading	Patent Bots	BluePencil	ClaimMaster	LexisNexis PatentOptimizer	
Docketing/reporting	Black Hills IP	helios	CLEARACCESS IP	PATTSY	leap
IDS prep & mgmt	syncIDS	MAXVAL	smartIDS	IPDAS	Tomburi
Prosecution	bigpatentdata	techson	[SmartShell]	IPDataLab	ktMINE
Strategic counseling	CLEARSTONE IP	ANTICIPAT	JURISTAT	PERCEPTION PARTNERS	Patentprufer

* Several companies have offerings spanning multiple categories.



IP Toolbox Approach